









# Diamond-Like Carbon for potential use as protective and high emissivity coating for future mirror suspensions

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#### Thin Film Centre at UWS

- Research facility created in 1999 in the University of the West of Scotland (Paisley).
  - Located approx. 10 km from The University of Glasgow.
- Aim of developing thin film deposition technology (particularly for industry).
- Commercial-scale deposition and characterisation equipment.
- Joined GEO and the LSC in September 2012 (group led by Reid).



#### **Facilities**

#### Deposition techniques

- Microwave-activated reactive sputtering
- RF and DC sputtering
- PECVD
- Plasma-assisted e-beam (evaporation)
- Recently purchased two ion sources for developing IBD
- Developing/characterising MBE with an industrial partner
- Currently developing optical coatings

#### Characterisation techniques include:

- SEM with EDX
- Raman Spectroscopy, FTIR
- Kelvin probe
- Surface energy (Contact angle)
- XRD
- Nanoindentor/microindentor & AFM
- Hardness/scratch/adhesion





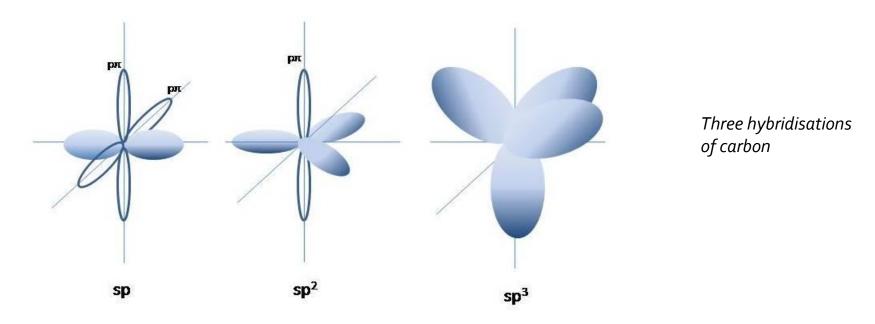


## DLC: Diamond-like Carbon applications in GW detectors

- The relatively <u>high emissivity</u> of DLC may be beneficial for cryogenic applications:
  - KAGRA are to coat baffle tubes with DLC for this purpose.
  - Compatible with UHV bakeout
  - Currently working on experimental coatings for VIRGO baffle tubes (SS304) multilayer modified DLCs at 2, 10 and 20µm total thickness
- The properties of DLC are attractive for use as a protective coating:
  - Can fabricate pinhole-free, relatively thick DLC using the hollow cathode CVD technique
  - Evaluation of using DLC for protecting low mechanical loss suspension components for future GW detectors
    e.g. coating cantilever springs (silica, silicon, sapphire) for reducing vertical thermal noise – see later.

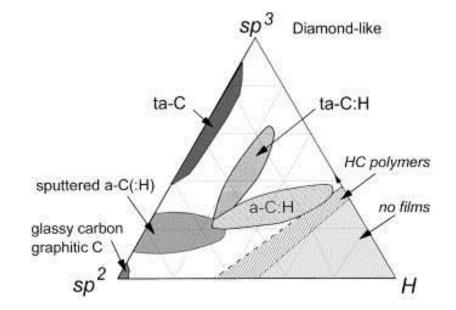
#### **DLC – Diamond-Like Carbon**

- Metastable form of amorphous carbon
- Consists of network of tetrahedrally and/or trigonally bonded carbon atoms as well as hydrogen (in some cases)
- Bonding varies from 100% sp2 (graphitic) to ~90% sp3 (similar to diamond)



#### DLC (continued)

- Term DLC can refer to several classes of material:
- ta-C tetrahedral amorphous carbon has up to 90% sp3 fraction
- ta-C:H tetrahedral hydrogenated amorphous carbon
- a-C amorphous carbon with <90% sp3 fraction</li>
- a-C:H hydrogenated amorphous carbon (carbon-hydrogen alloys)

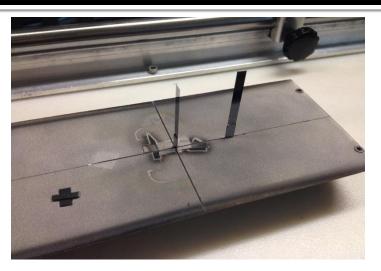


A ternary phase diagram relating the compositions of the various amorphous carbons and amorphous carbon-hydrogen alloys [1]

[1] J. Robertson, Jpn. J Appl. Phys. 50 (2011) 01AF01

### Properties of DLCs

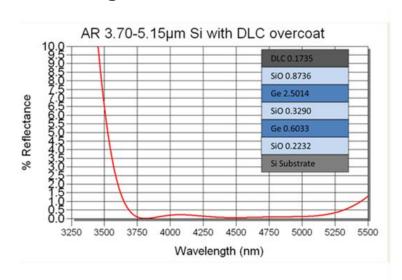
- Hard typically ~12GPa (a-C:H type), E<sub>R</sub>~100-120GPa
- Excellent protective properties :
  - Anti-corrosive
  - Smooth, conformal coating (non-directional deposition process)
  - Despite high intrinsic stress, can deposit multilayers up to ~70µm total thickness
  - Low-friction useful in e.g. engine components
  - -High emissivity
  - -Largely transparent in infrared useful in IR optical coatings

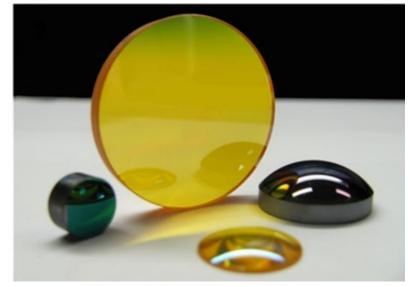




### Synthesis and applications

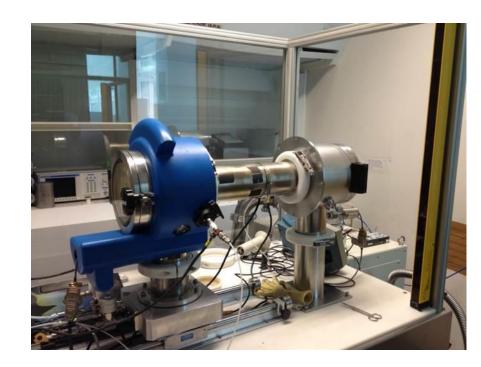
- Deposition by a wide range of methods including PECVD, HC-PECVD, RF sputtering, evaporation, MSIBD, pulsed laser deposition
- Applications include infrared optics, gas barrier coatings, protective coatings for corrosive / abrasive environments, accelerator coatings
- Not currently being considered for use in GW detector mirror coatings





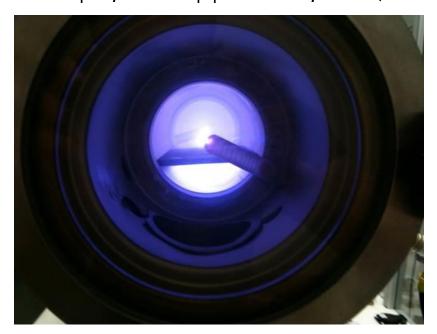
#### **UWS DLC Process**

- Hollow cathode PECVD
- Pulsed-DC waveform applied to enable dissipation of charge during off cycle (DLC is insulative, and charging of growing film will eventually lead to arcing and pinholing of coating)
- Multilayer or single-layer process utilising hydrocarbon and other precursors
- Can deposit hydrogenated DLC, modified DLC, a-Si:H, a-Si:C, a-Ge:C...

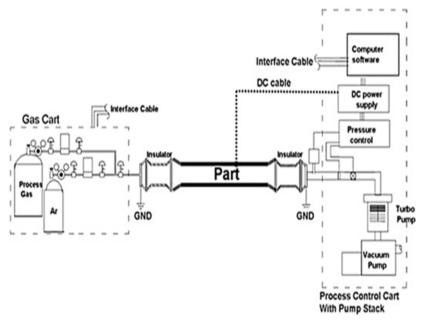


### Coating Deposition – HC-PECVD

- System can accommodate various lengths / diameters of pipe
- Modification of system allows coating different substrate geometries: flat, irregularly shaped, exterior pipe surfaces, fibres (in theory)



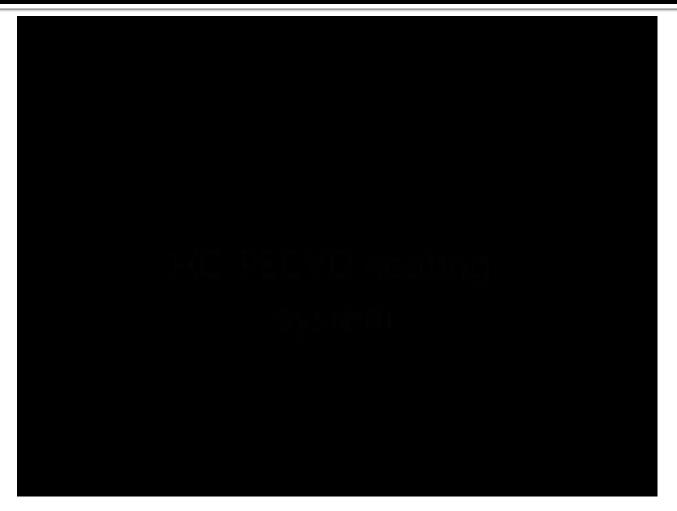
HC-PECVD system, 4x12" pipe chamber with Al stage (Thin Film Centre, UWS)



Schematic of hollow cathode pulsed-DC PECVD system [2]

[2] D.Lusk, M.Gore, W. Boardman, T.Casserly, K.Boinapally, M.Oppus, D.Upadhyaya, A. Tudhope, M. Gupta, Y.Cao, S.Lapp, Diamond Rel. Mater. 17 (2008) 1613

## Sub-One Technology HC-PECVD System



### DLC: thermal noise (on sapphire cantilever spring)

• Mechanical loss of DLC on silicon at room temperature  $\sim 3 \times 10^{-4}$ .



See talk by A. Cumming (ET Meeting, Hannover, Oct 2013)

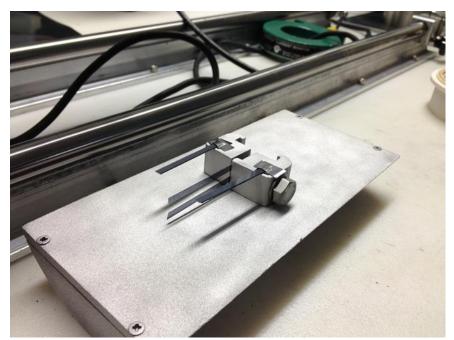
Sapphire suspension – without DLC coating applied:

Component		Energy ratio %	Loss of component	Loss contribution to total
Fibre main section		97.38	4.44E-07	4.32E-07
Fibre ends		1.38	8.00E-08	1.44E-09
В	lade	1.24	5.2E-10 at 10Hz	6.45E-12 at 10Hz
Blade clamps		0.0036	1.00E-04	3.65E-09
Connection - Bond		0.0013	Yet to be measured	
			Total loss	4.36E-07
			Dissipation dilution	13.5 (6.75)
			Pendulum mode løss	3.3E-08 (6.6E-8)

- Energy ratio for 1  $\mu$ m DLC on 1  $\mu$ m thick Al $_3$ O $_3$  cantilever spring is ~ 4  $\times$  10<sup>-3</sup>, contributing to a loss of 1 $\times$  10<sup>-6</sup>.
- Contribution to loss of bounce mode of suspension is 1.24% and therefore ~1× 10<sup>-8</sup> (approx. 2% vertical suspension TN).
- Can be reduced by reducing DLC thickness (and lower T?).

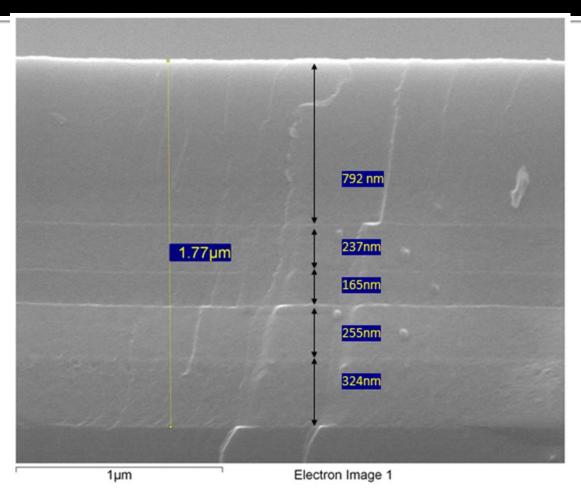
## Strength testing of Multilayer DLCs for silicon suspensions

- 5-layer modified DLC coatings tested at 3.5µm total thickness
- Initial results encouraging, showing improvement of breaking stress in some cases
- Greater sample population needed!



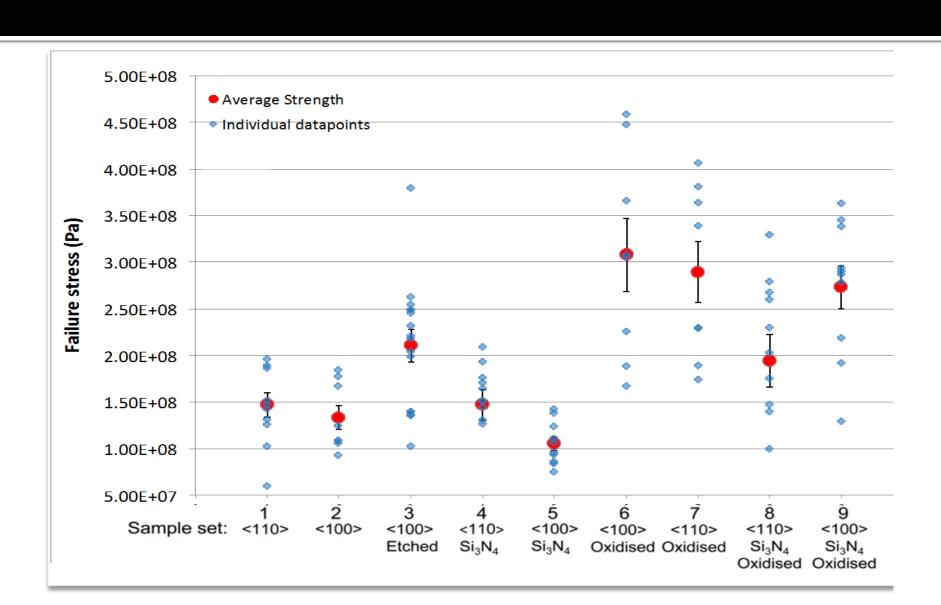


## 5-layer modified DLC on Si substrate

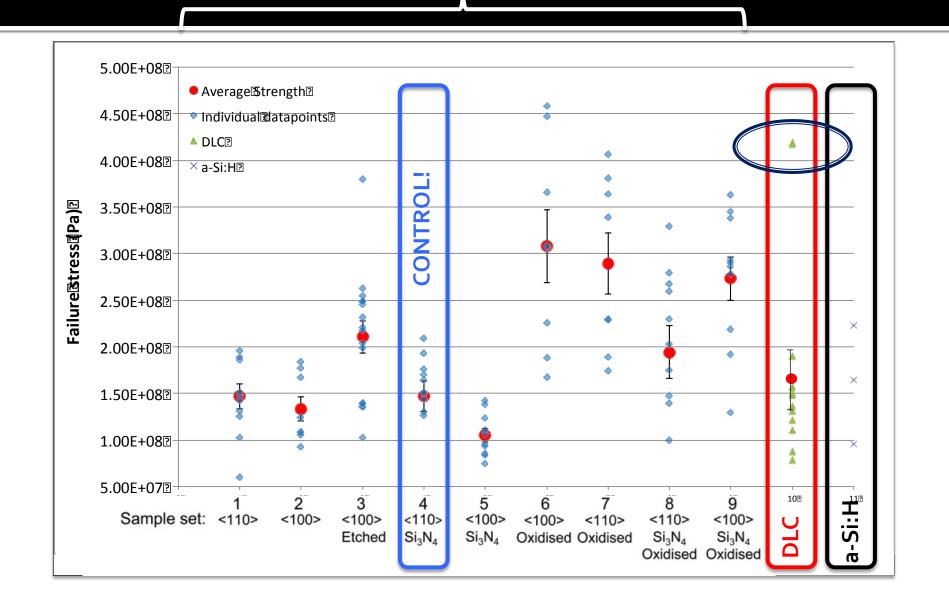


 SEM cross-section of 5-layer modified DLC deposited on silicon by HCPECVD at 400W power.

#### Cumming et al., Class. Quantum Grav. 31 (2014)



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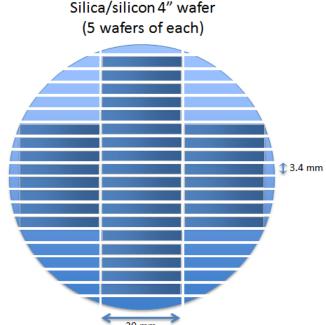


## Coating strength testing (currently underway)



-12 silicon strips, edge polished + extended Ar etch + magnetron silica coating

-12 silicon strips, edge polished + magnetron silica coating



- Multilayer DLC coatings are ~3.5µm thick, single-layer coatings are 1µm thick
- To be repeated for silica and sapphire substrates too

#### Conclusions

- DLC on test silicon suspension shows no significant loss in strength compared to the control / untreated Si (evidence that DLC coatings may increase strength) – further work with a much greater number of samples is underway
- DLC will contribute negligible thermal noise associated with cantilever springs
- Future work includes:
- Measurement of mechanical strength and mechanical loss at low T of DLC coated components.
- Investigate DLC coatings on silica and sapphire substrates available
- Studies on the effect of clamping/jointing DLC coated cantilever springs
- Investigate DLC coatings on silicon and sapphire suspension fibres (here the mechanical loss and relative thickness of the DLC films are critical in the suspension thermal noise – more challenging).
- Some studies are underway on coating silicon suspensions with a thin layer of a-Si:H to evaluate the effect on strength (e.g. from filling in microcracks from manufacturing process) and on thermal noise

### Acknowledgements

Thanks to Dr Liz Porteous at UWS for SEM imaging and Gerry O'Hare for (much) substrate preparation.

Thank you for your attention!